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(12) **United States Design Patent**
Chih

(10) **Patent No.:** **US D476,020 S**

(45) **Date of Patent:** **** Jun. 17, 2003**

(54) **INNOVATIVE MICROMETRIC MEASURING INSTRUMENT**

5,694,242 A * 12/1997 Omi 359/369

* cited by examiner

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(**) Term: **14 Years**

(57) **CLAIM**

The ornamental design for an innovative micrometric measuring instrument, as shown and described.

(21) Appl. No.: **29/163,809**

DESCRIPTION

(22) Filed: **Jul. 15, 2002**

(51) **LOC (7) Cl.** **16-06**

(52) **U.S. Cl.** **D16/131; D10/46**

(58) **Field of Search** **D16/131; D10/46; 359/392, 368, 369**

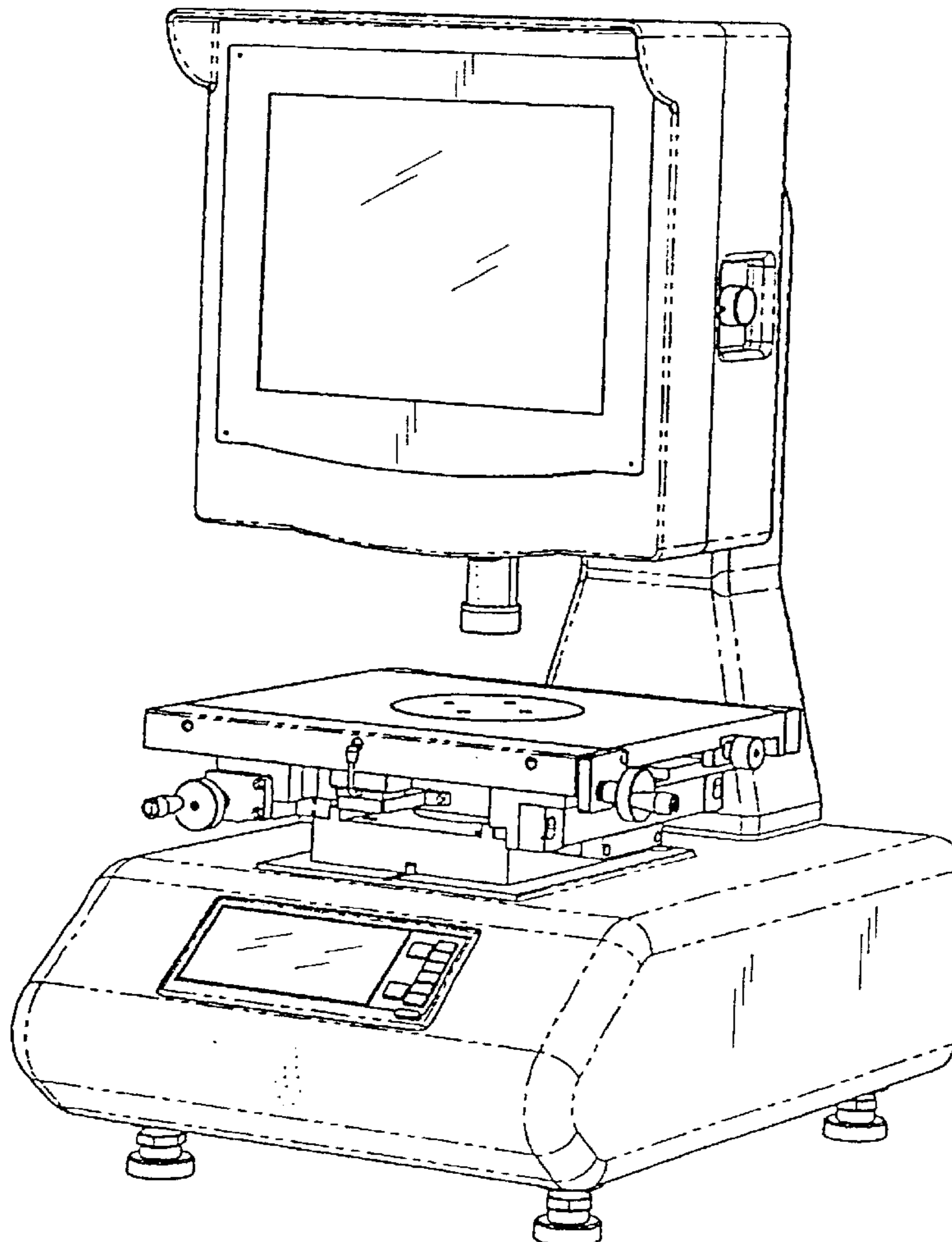
FIG. 1 is a front elevational view of an innovative micrometric measuring instrument showing my new design; FIG. 2 is a rear elevational view thereof; FIG. 3 is a left side elevational view thereof; FIG. 4 is a right side elevational view thereof; FIG. 5 is a top plan elevational view thereof; FIG. 6 is a bottom plan elevational view thereof; and, FIG. 7 is a top, front and right perspective elevational view thereof.

(56) **References Cited**

U.S. PATENT DOCUMENTS

D359,059 S * 6/1995 Omi D16/131

1 Claim, 7 Drawing Sheets



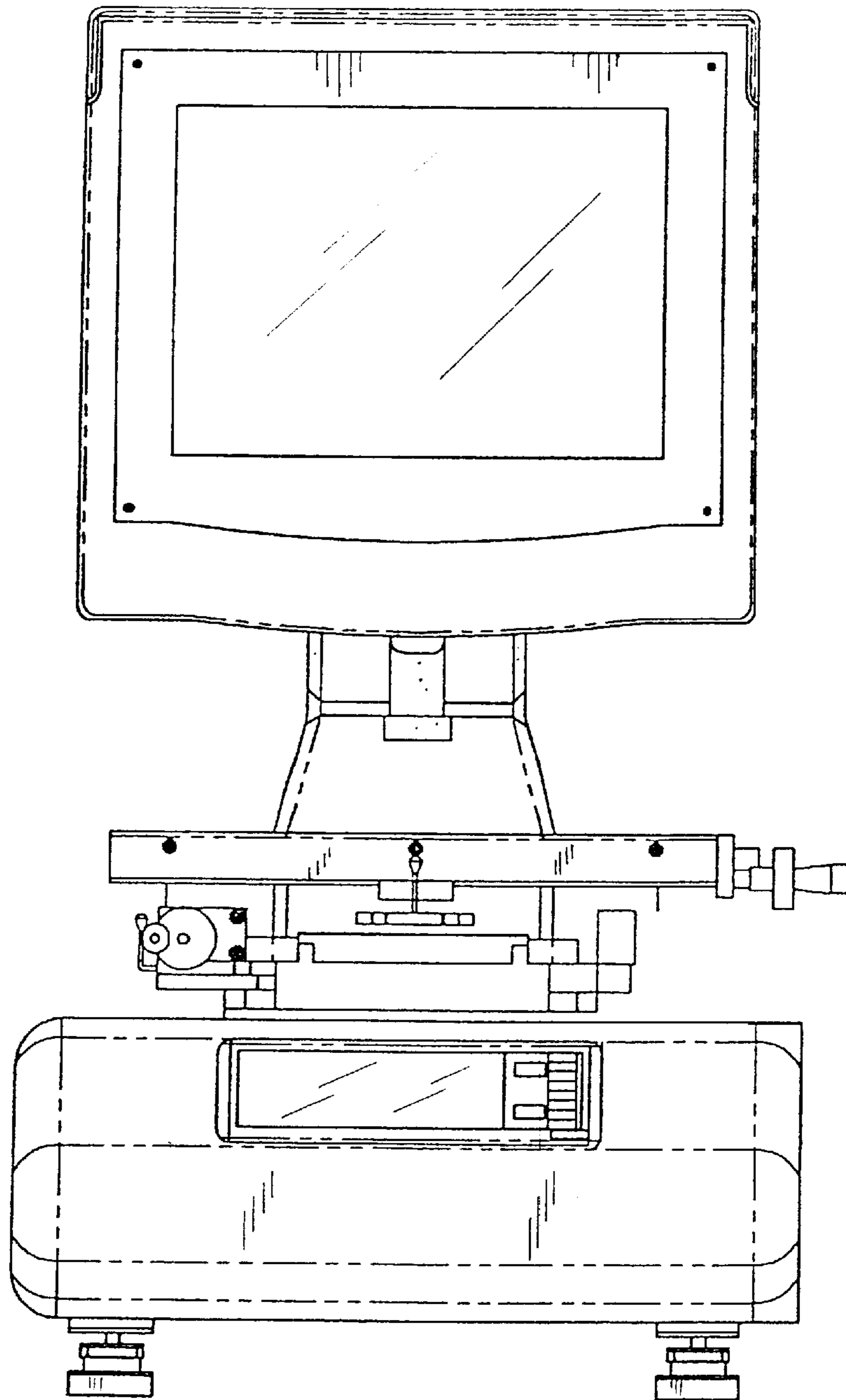


FIG. 1

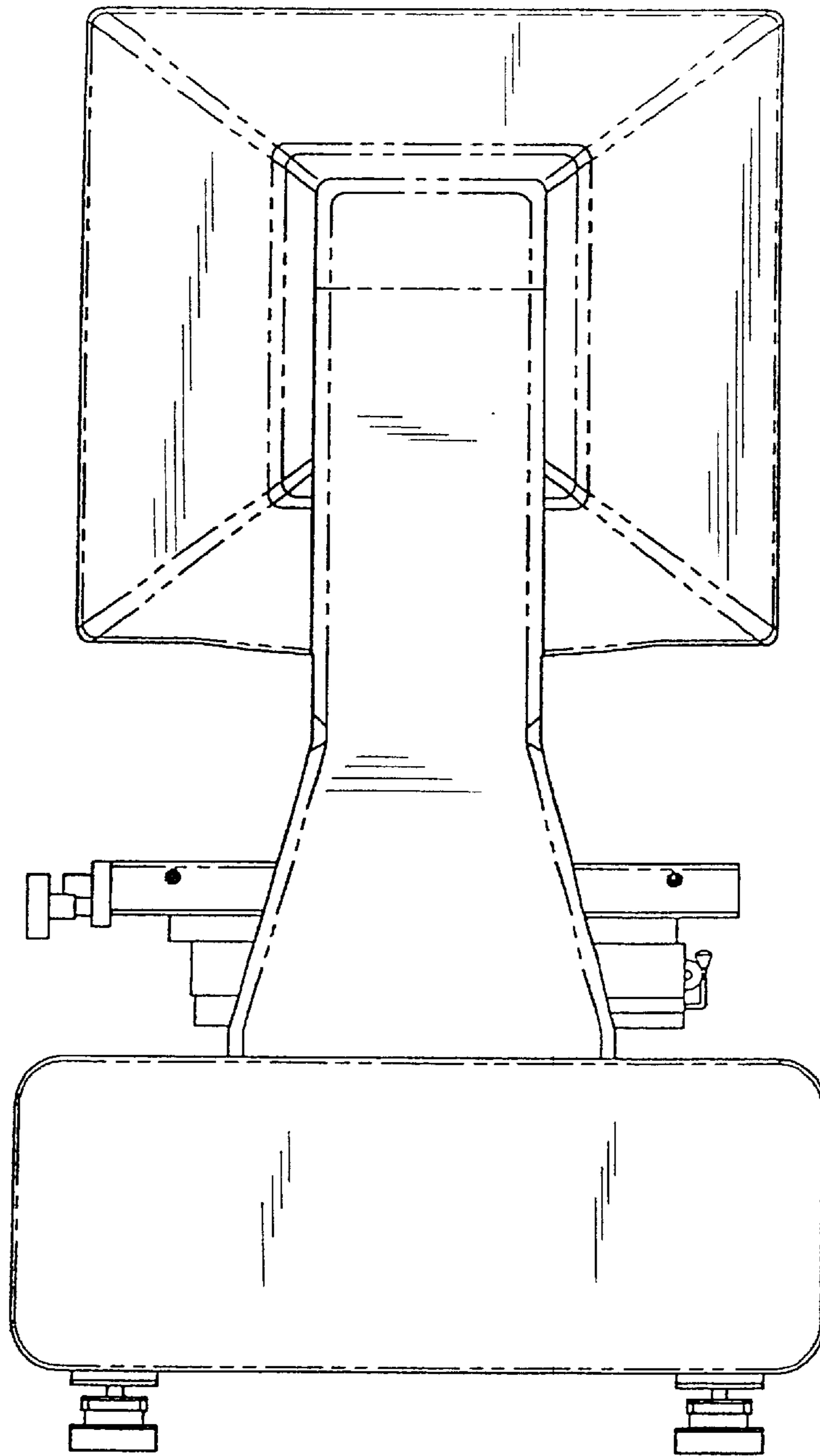


FIG. 2

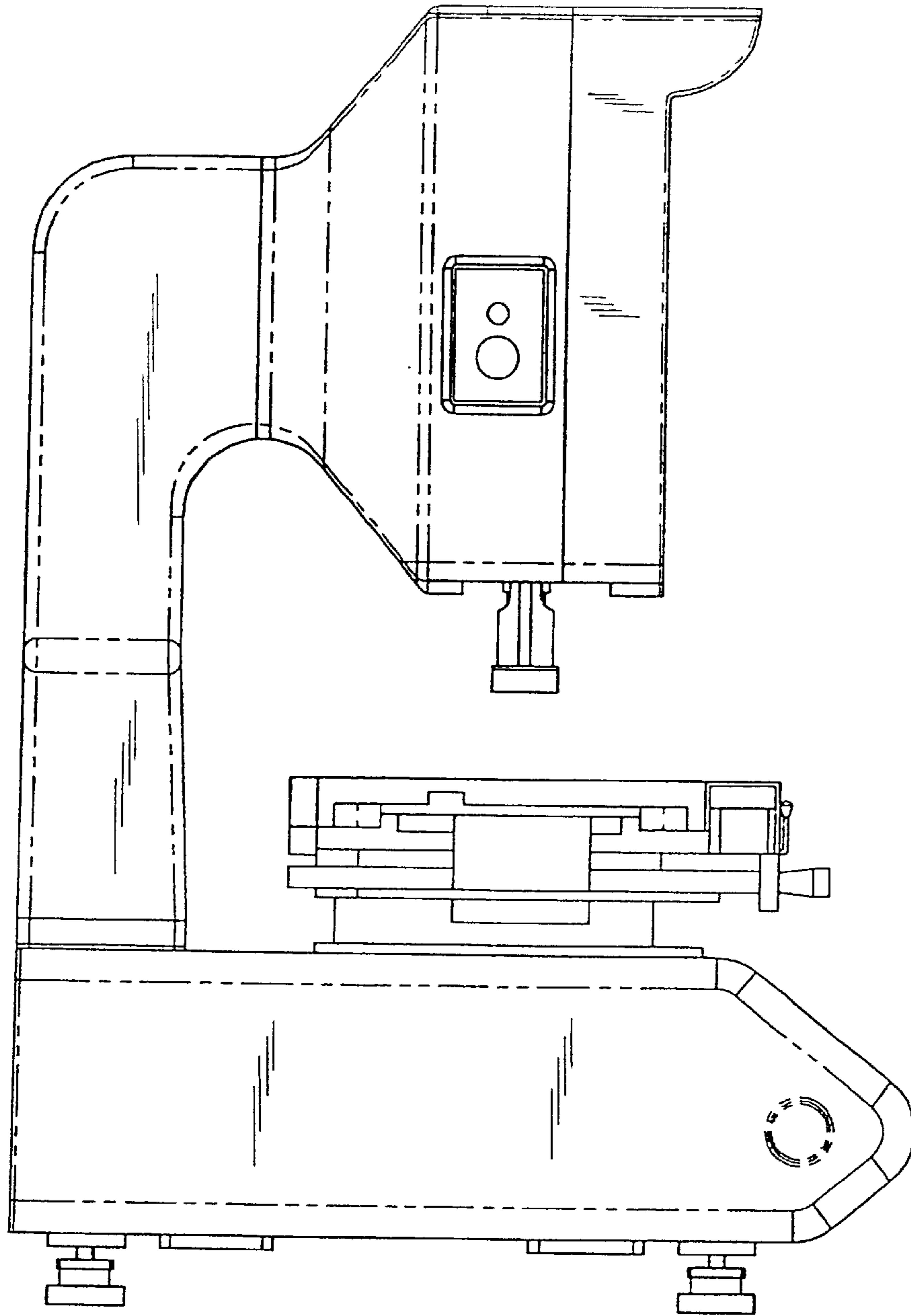


FIG. 3

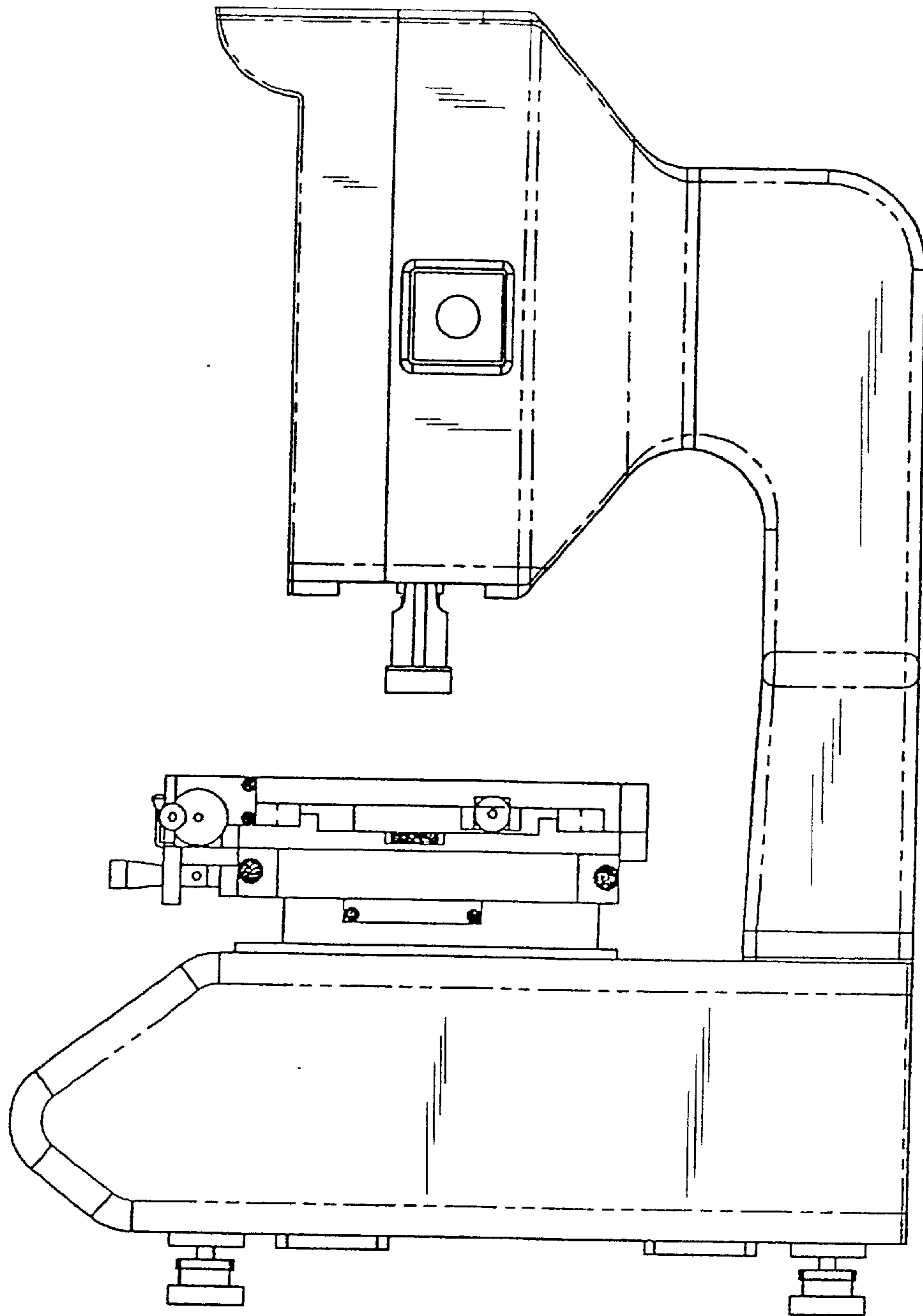


FIG. 4

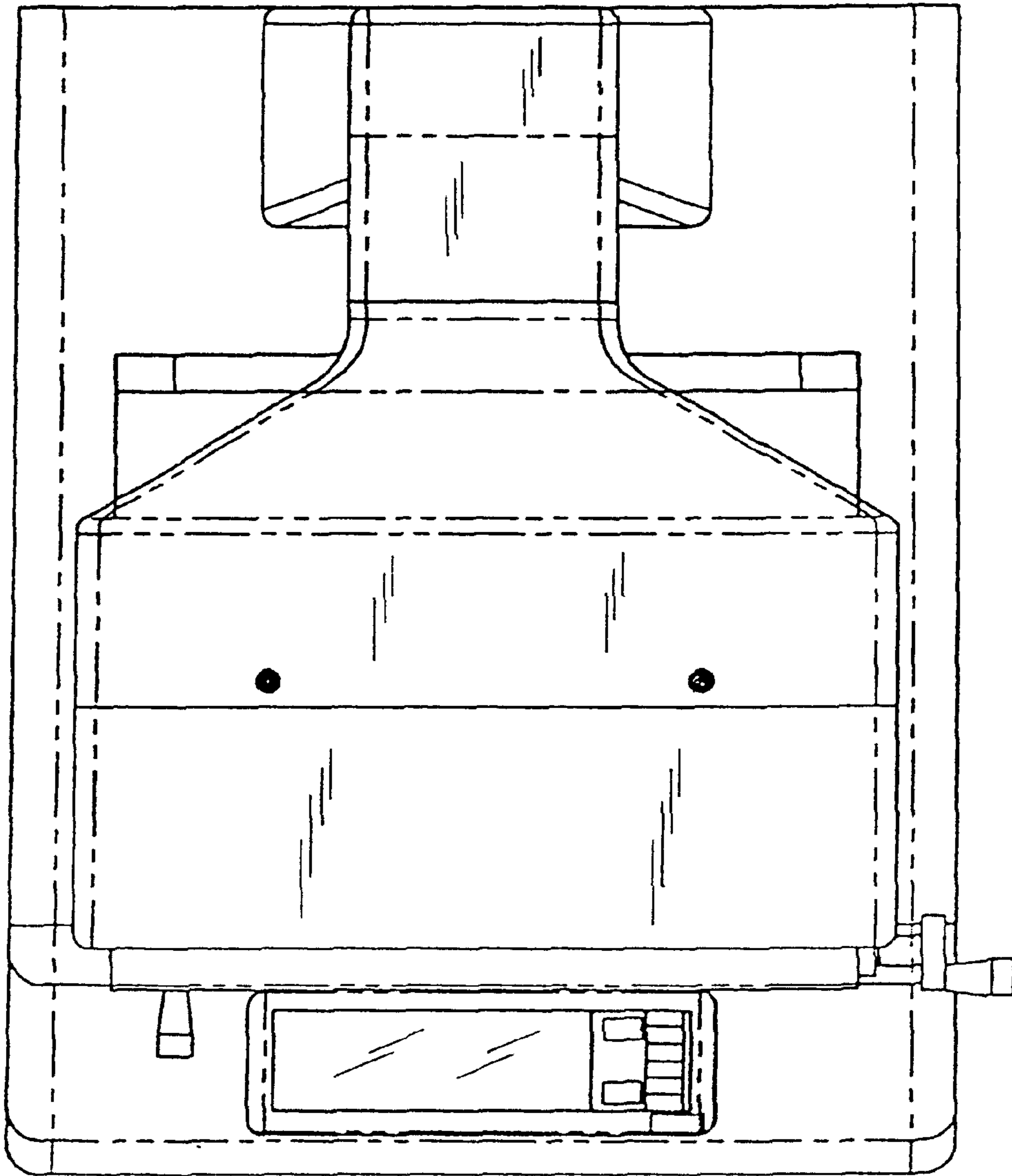


FIG. 5

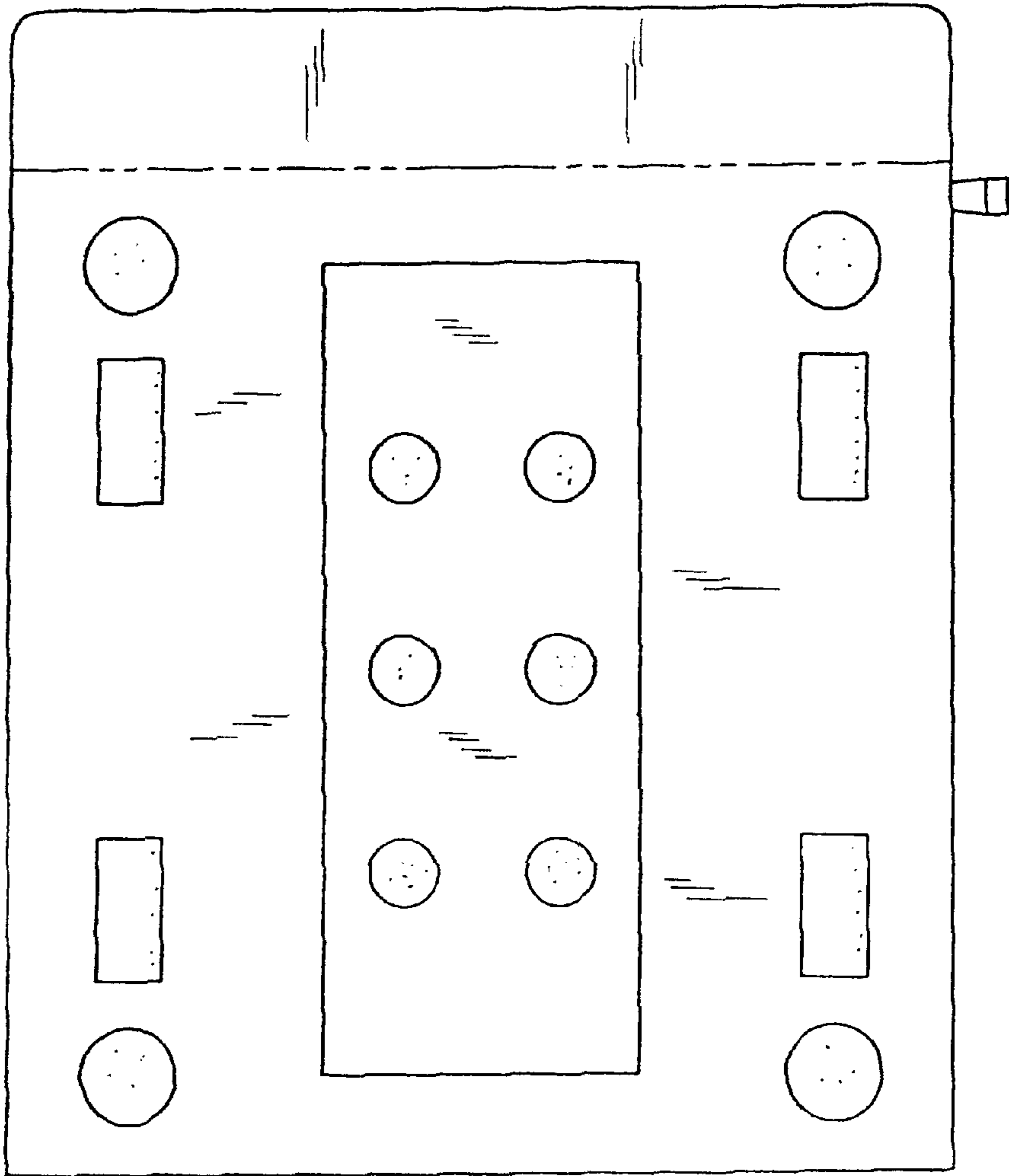


FIG. 6

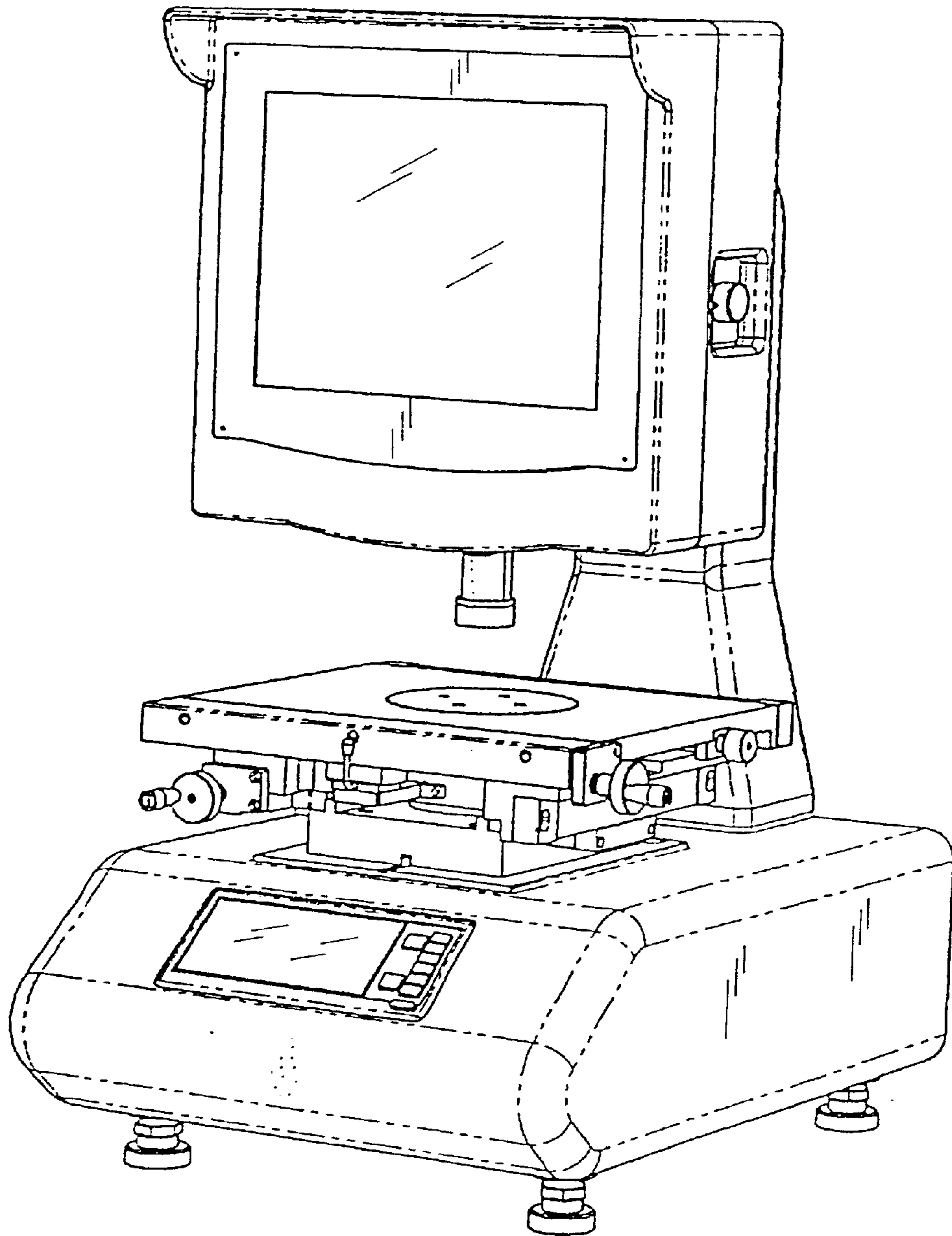


FIG. 7